

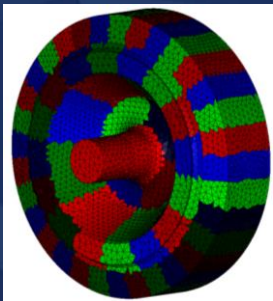
P³ 2021

2021 Photocathode Physics for Photoinjectors Workshop
SLAC National Accelerator Laboratory
10-12 November 2021

Virtual

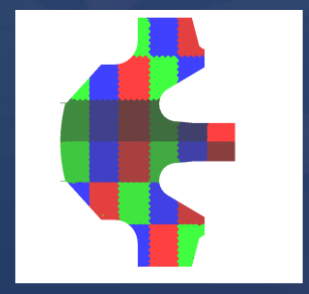
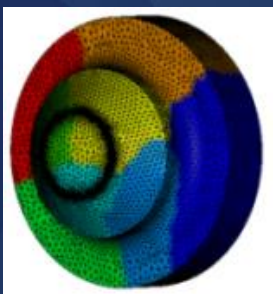
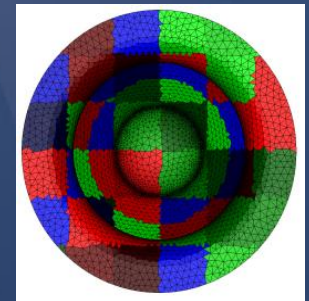


Chemical and Geometric Contributions to Intrinsic Emittance for Electron Emission



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Leidos, Inc.

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Work supported by NRL and
Leidos

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- I. Background and Motivation/Discussion**
 - II. Chemical Contribution to Emittance (Work Function Variation)**
 - III. Artificial (Ordered) Geometric Surface Array Contribution to Emittance**
 - IV. Less Artificial (Non-Ordered) Geometric Surface Array Contribution to Emittance**
 - V. Comparison of Contributions to Emittance**
 - VI. Application: 1 Micron Work Function Patch Size with 10 Micron Feature Size**
- I. Summary**

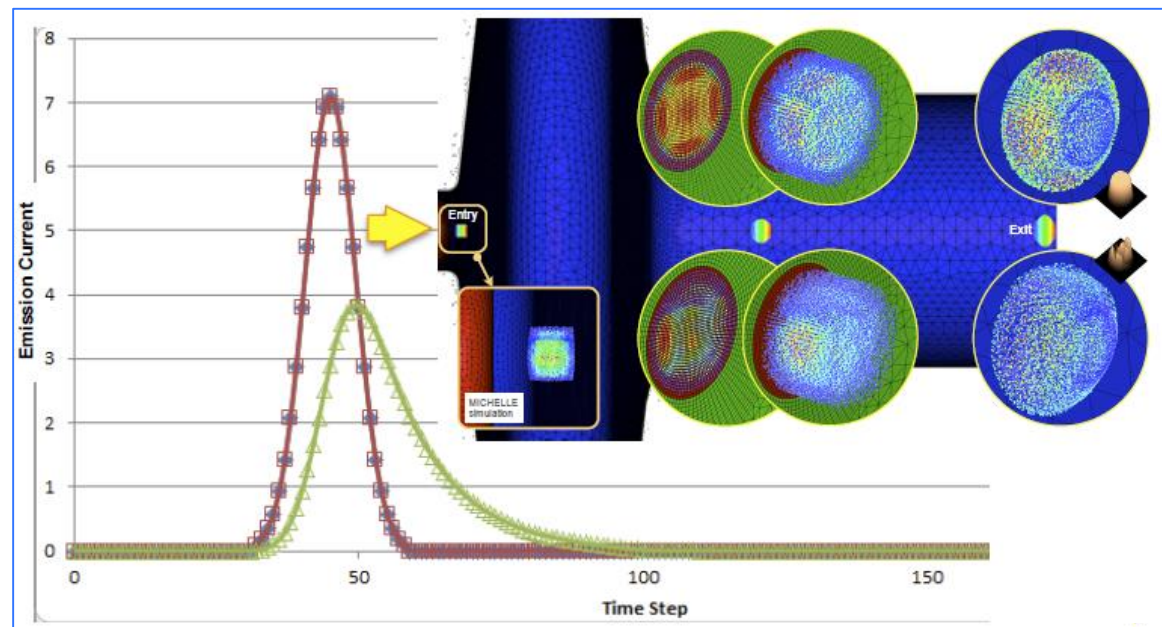
1. Regime of interest:
 - Presentation for regime where space charge effects are not important.
2. Geometric Contribution:
 - Previously reported on a “bumpy” surface formulation that captures the characteristics of surface features on some photoemitters enabling the inclusion of mean transverse energy (MTE) in calculations.
 - Here we use the mathematical surface as a boundary to our mesh generation.
 - Confirmed that simulation reproduces analytical solution for particle distributions and optics.
3. Chemical Contribution
 - In the DARPA INVEST program we showed that the microscopic makeup of the emission surface is the cause of the shape of the Miram curve
 - Miram Curve: Indicates anode current for thermionic emitters as a function of emitter temperature.
 - Curve rolls over as space charge begins to limit the current that makes it out of the potential well that forms.
 - Smooth extended Roll-Over shape is primarily caused by emitter surface chemical makeup
 - Otherwise a relatively sharp transition takes place.
 - Shown to have a significant effect on intrinsic emittance
4. Capturing Emission Distribution
 - Previously have shown that micro/meso-scopic effects lead to specific velocity distributions and emittances.
 - Developed an ability to capture velocity distributions for sample patches and present this distribution to macroscopic-sized regimes.
5. Combination of Effects
 - How does this all play out?

Photot emission Model

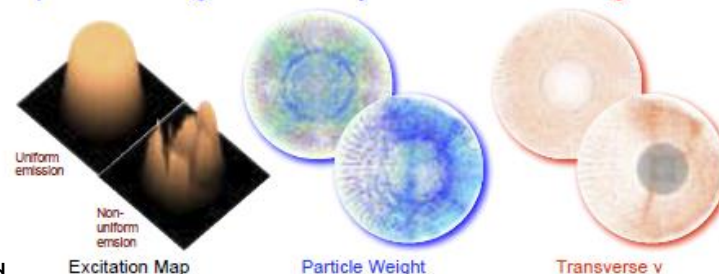
- Delayed Emission model incorporates material properties (m; EG; n & k; R; ; DOS) for metal, semiconductor, and coated material photocathodes
- Geometry / Field enhancement modeled using an impulse approximation to the launch velocity of electrons
- Ability to characterize and model surface roughness
 - Capture emission statistics

Particle Emission Library

- Have separated out the entire MICHELLE emission model set
- Now exists in a library form
- Callable from
 - Leidos' MICHELLE (C++)
 - Leidos' eBEAM
 - NRL's NEPTUNE
 - AFRL's ICEPIC
 - Fortran 90 (& F77) – codes like LBL's IMPACT-T

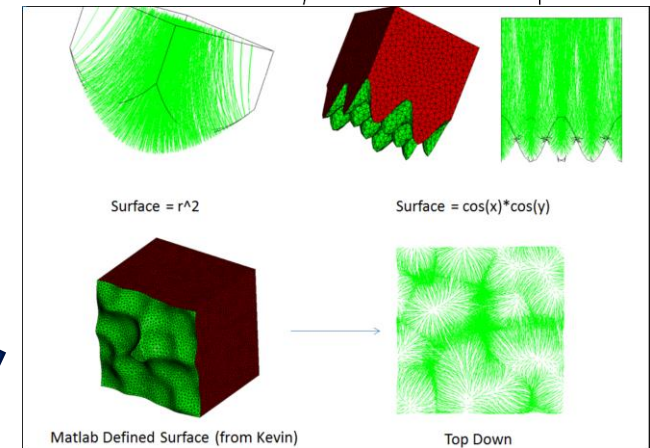
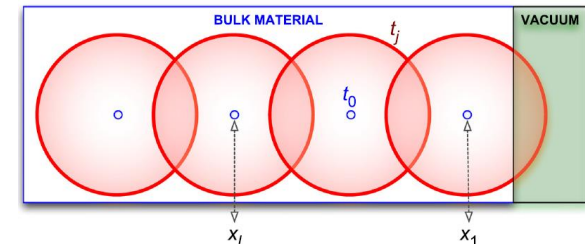


Nonuniformity + geometry ↔ transverse
Space Charge + density variation ↔ longitudinal

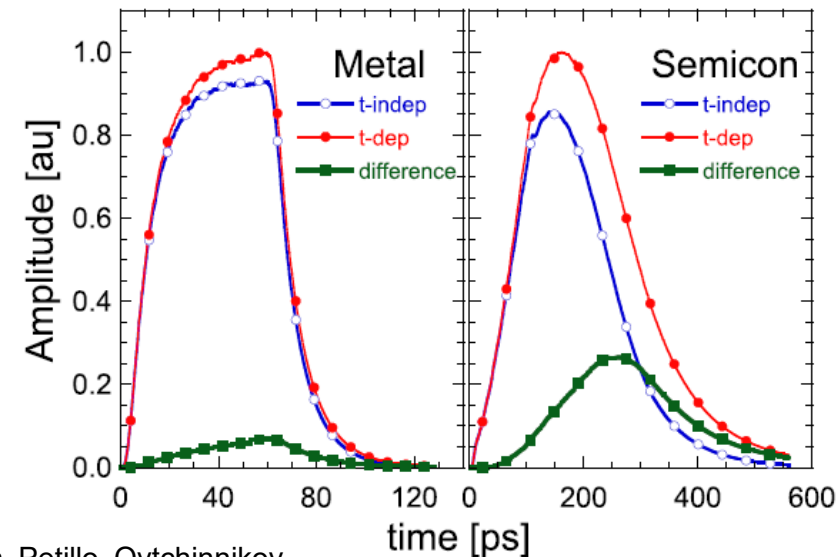
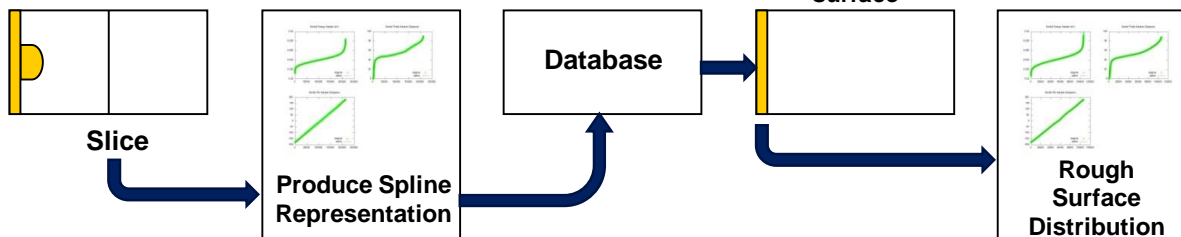


Particle Emission Models:

- New delay model (laser penetrates deep into the material)
- Rough surface model - analytic
 - Produces distributions allowing MICHELLE to re-emit from a macroscopically flat surface and capture these dynamics
 - Method works with SD & TD
- All the above properties affect the intrinsic emittance and the formation of beam halos & tails



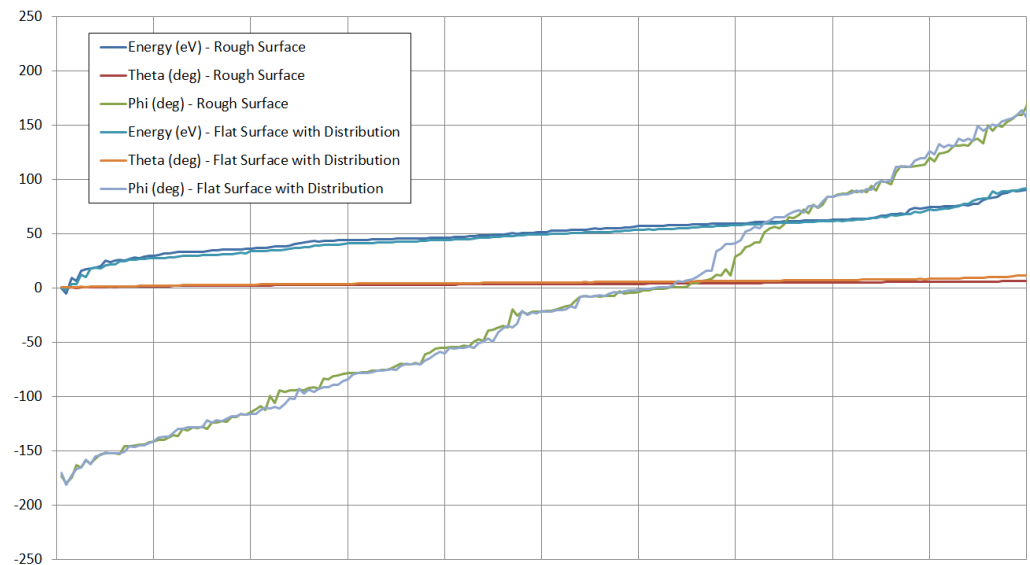
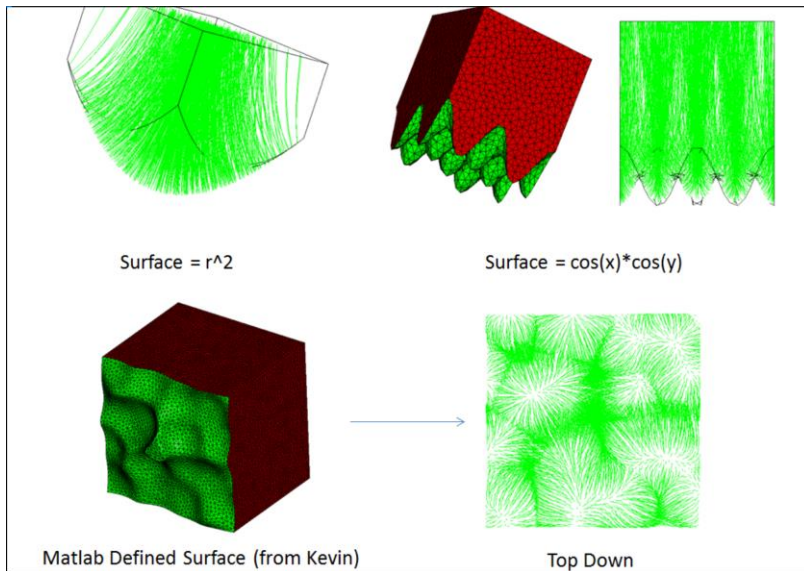
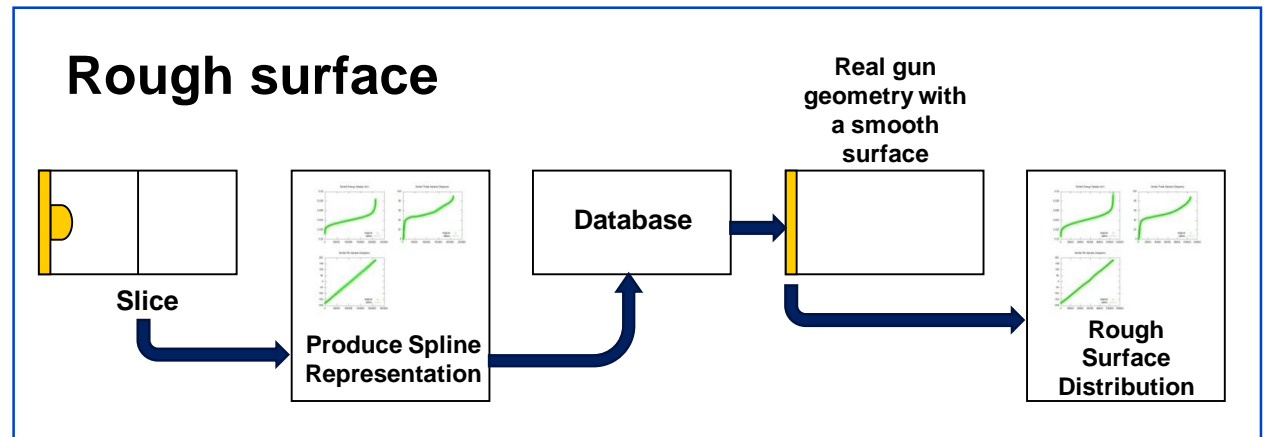
Rough surface



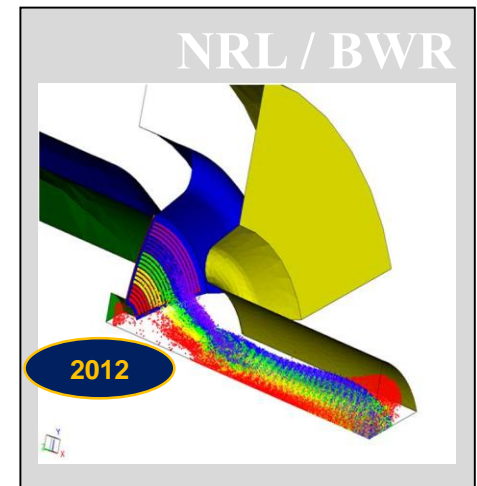
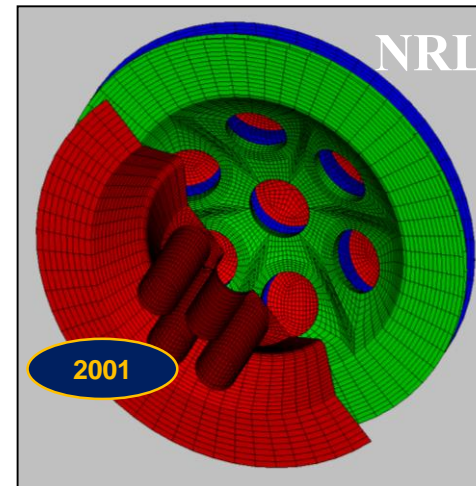
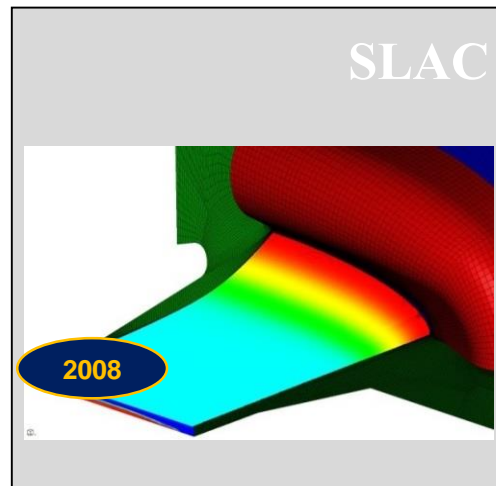
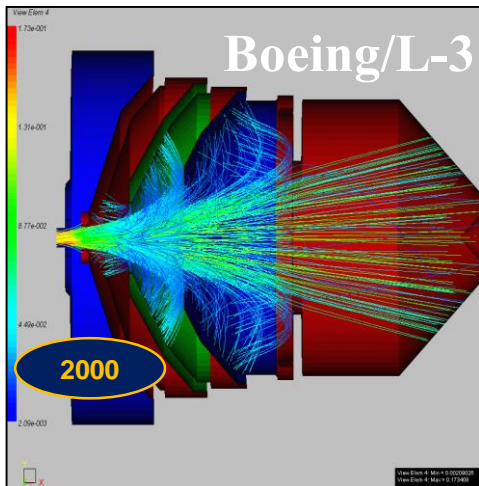
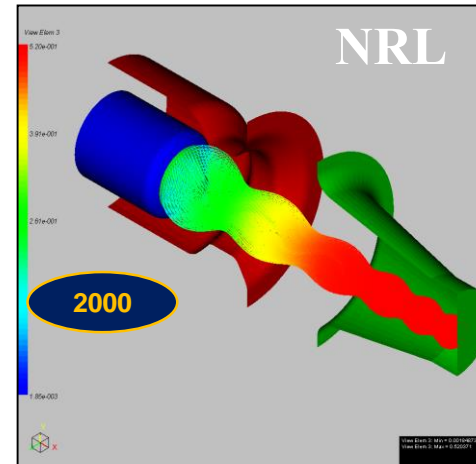
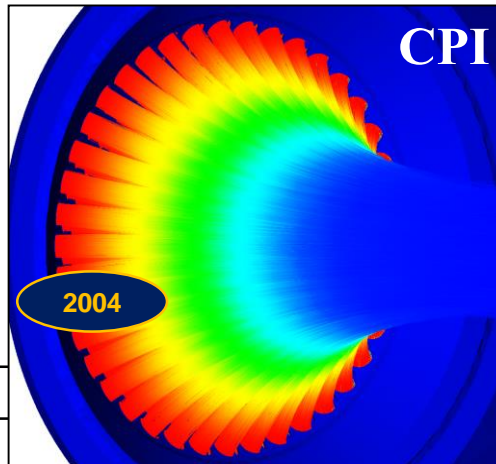
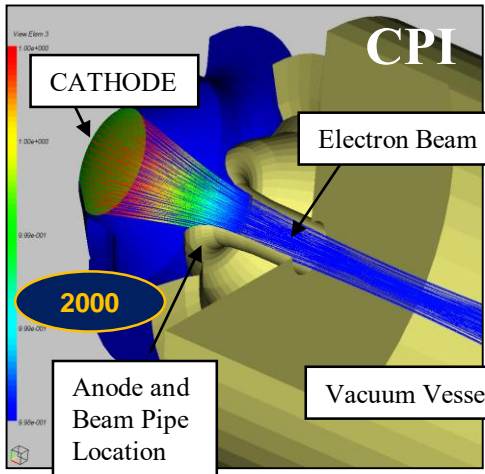
“Modeling emission lag after photoexcitation”, Jensen, Petillo, Ovtchinnikov, Panagos, Moody, & Lambrakos, J. of Applied Physics 122, 164501 (2017);

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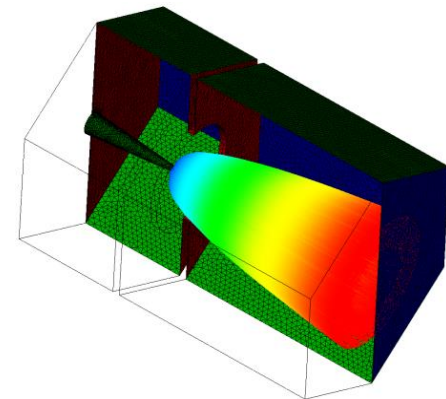
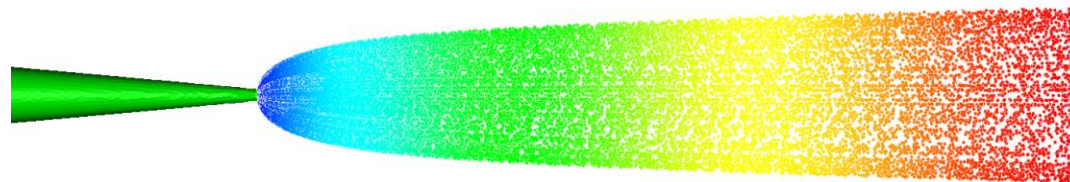
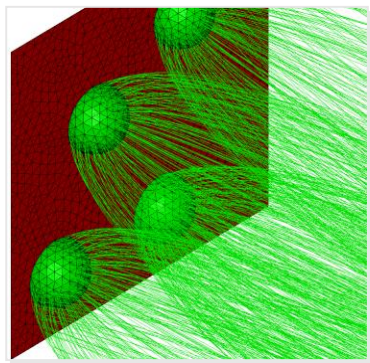
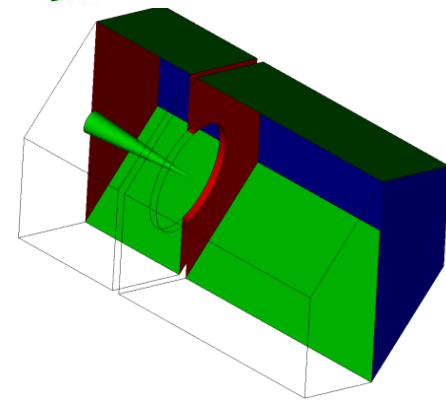
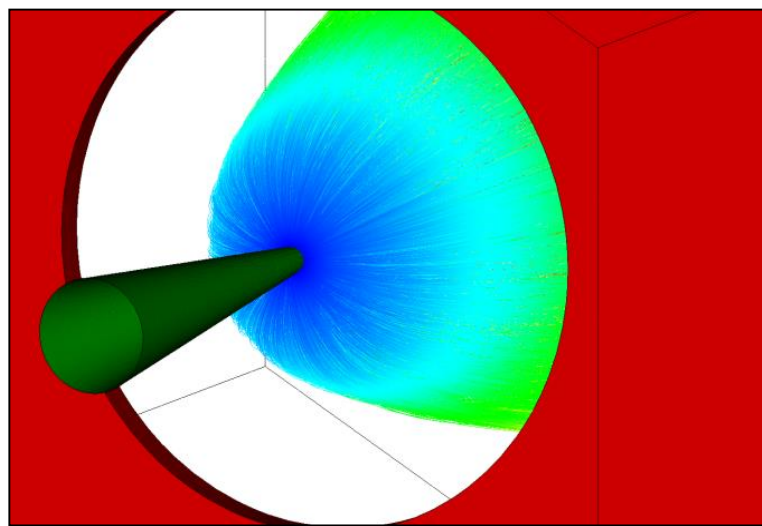
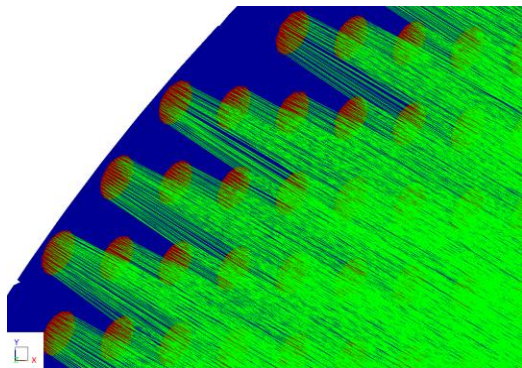
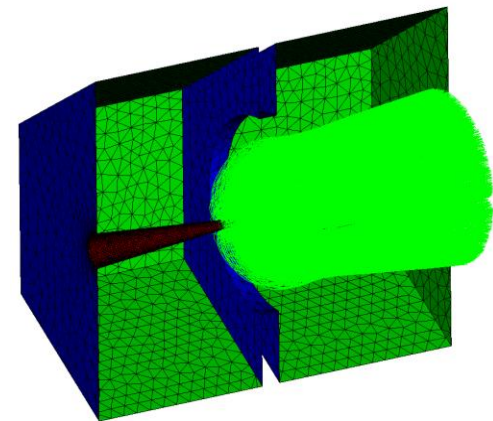
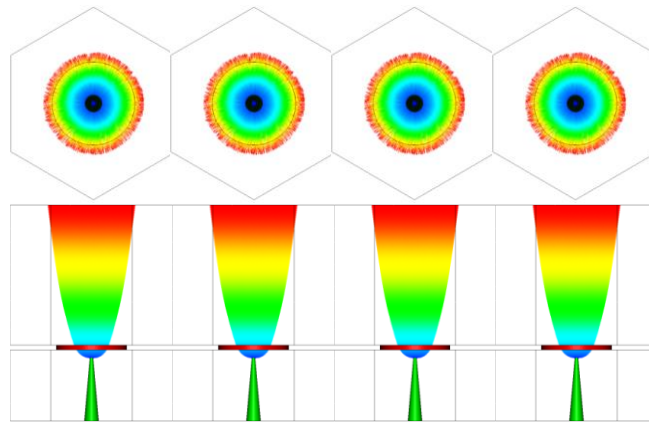
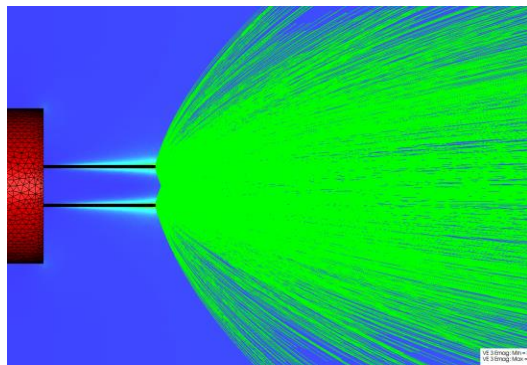
- Methodology used to capture emitted velocity and angular distribution
- Allows beam distribution calculated in a micro/meso-scopic simulation to be sampled and launched in a large scale macroscopic simulation



Traditional Voyager/MICHELLE Problem Classes



MICHELLE VE Problem Classes: Field Emission Arrays



□ Applications

- Charged Particle Beam Optics for VE, HPM, DE, Accelerator components (FELs)
- Electron guns, beam sources, transport, electron collectors
- Beams in RF cavities: RF photocathodes, IOTs → including beam loading

□ Algorithms

- Solvers
 - Steady-State ES PIC - “Gun” algorithm
 - Time-Domain ES PIC
- 2D & 3D Finite Element Electrostatic/Magnetostatic (self) Particle-in-Cell
 - Linear, quadratic, cubic bases
- Domain-decomposed Unstructured, Structured, & Hybrid mesh capable
 - Elements: Tetrahedra, hexahedra, prisms, pyramids, quads, triangles
- Circuit model: e.g., IOT RF cavity including beam loading
- Many physics-based emission models (Jensen/Dionne)

Gun (source), Collector and Transport Charged Particle Optics Modeling Code

Finite Element Approach – linear, quadratic, cubic

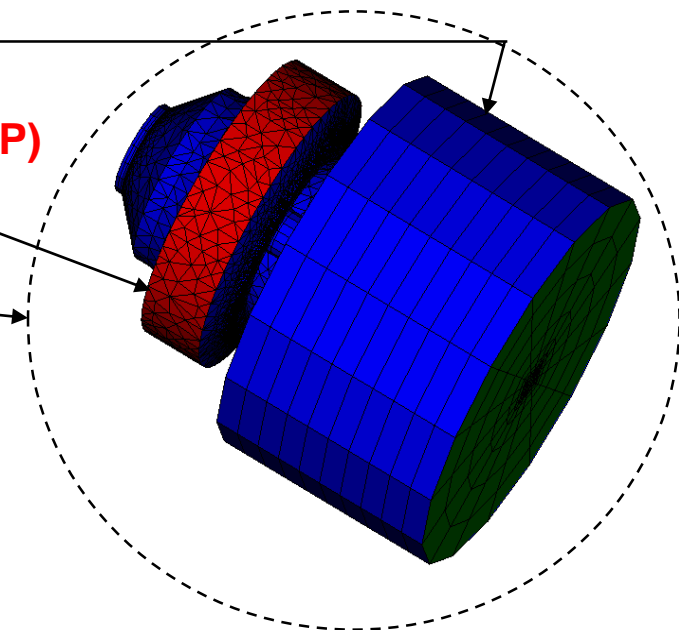
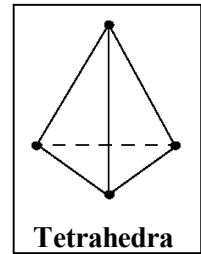
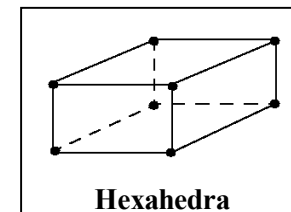
Two Electrostatic Particle-In-Cell (ES-PIC) methods

- SS: Equilibrium Steady-State PIC (“gun model”)
- TD: Time Domain ES PIC

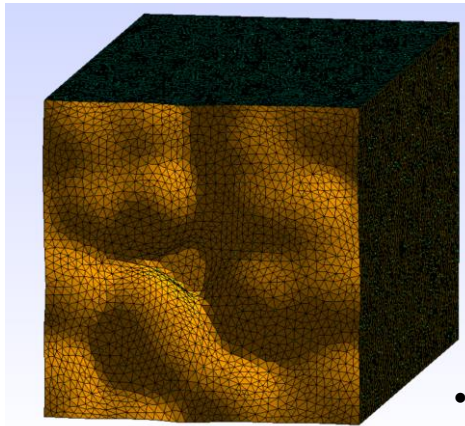
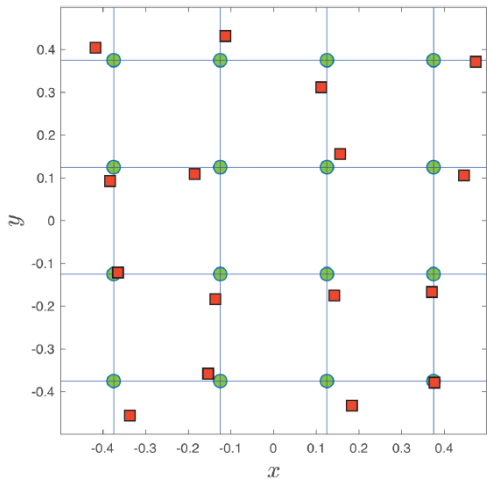
Grid System Supported - conformal

Within Voyager GUI with ICEM-CFD mesher

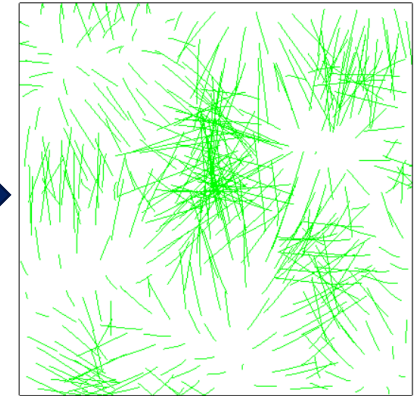
- Supports most high-end CAD modelers (**primitives: CUBIT, CAPSTONE, Gmsh, A-MP**)
 - we use SolidWorks
- Structured Mesh (**ICEM, Gmsh**)
 - 3D Multi-block, Hexahedral
- Unstructured Mesh (**ICEM, CUBIT, CAPSTONE, Gmsh, A-MP**)
 - 2D - Triangle, Quadrilateral
 - 3D - Tetrahedral, Hexahedral, Prism, Pyramid
- Hybrid Mesh
 - Single run Structured mesh and Unstructured mesh
 - Benefits: Compact data storage of a structured mesh for computational efficiency and improved particle tracking



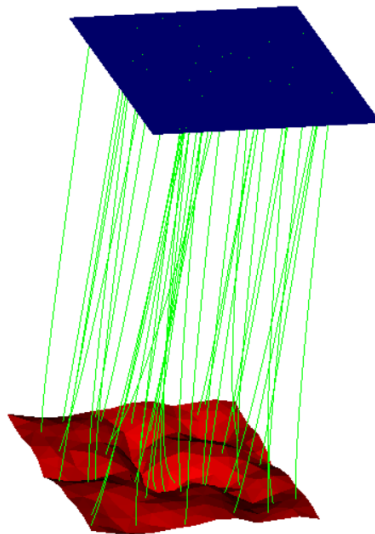
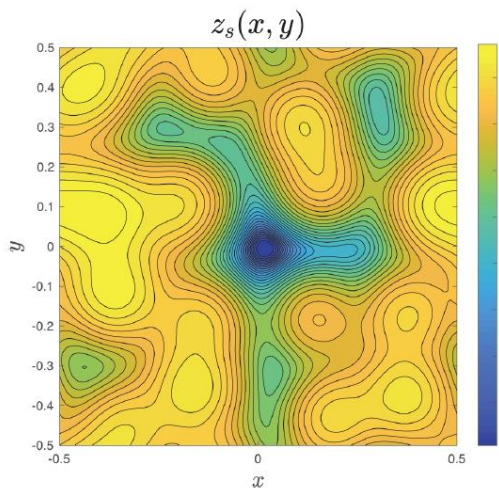
**Fully integrated into Analyst-MP (A-MP),
Cadence/AWR’s full-featured EM modeling
environment**



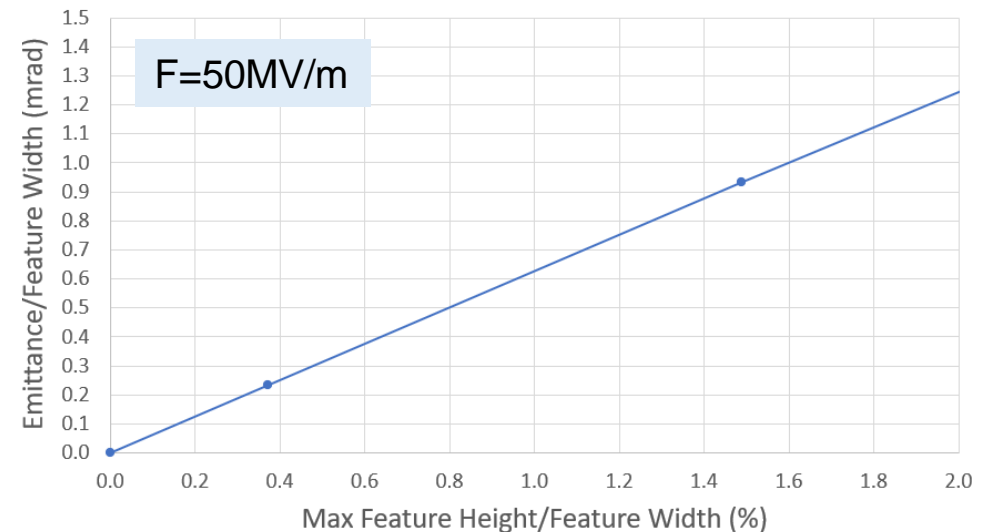
- Top down view of trajectories
- Macroparticle count reduced for emphasis



RMS Feature Height: 0.0346
Max Feature Height: 0.186
Feature Width: 0.25

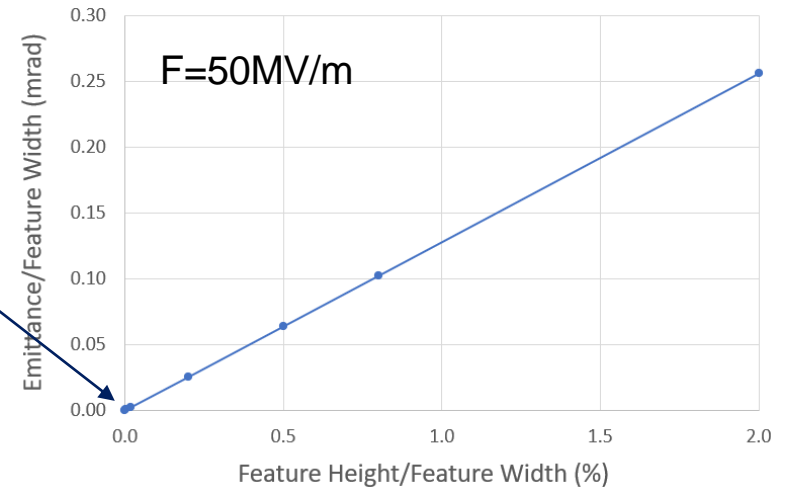
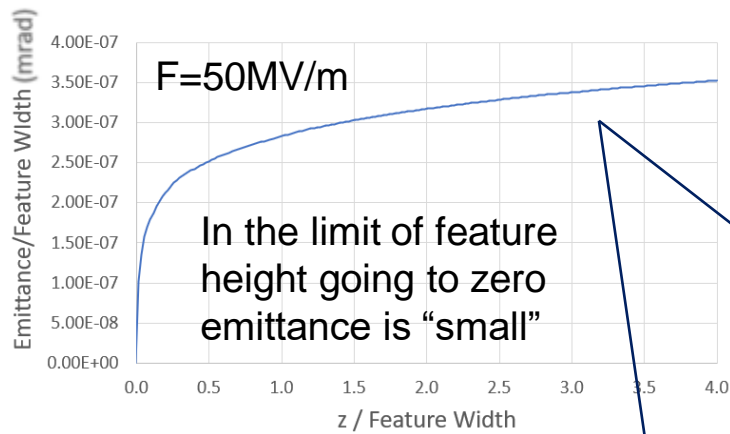
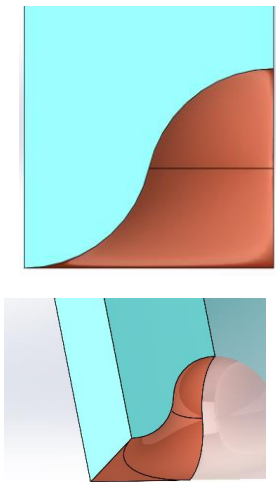
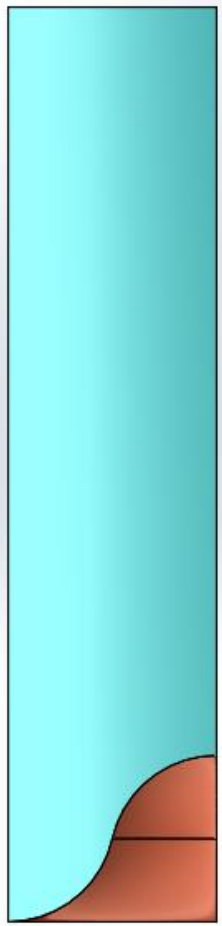


- Scale amplitude of rough surface
- Emittance ~4x higher than simple hemisphere
 - Even when normalized against max height feature

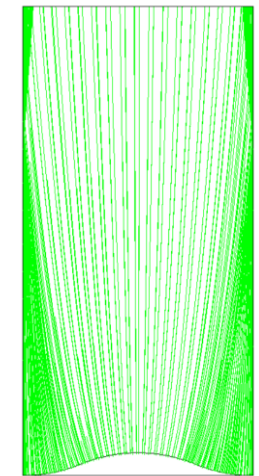
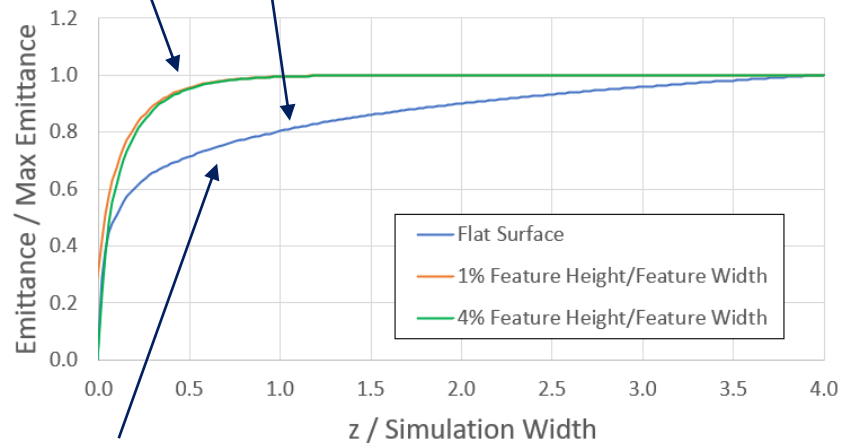


K.L. Jensen, M. McDonald, O. Chubenko, J.R. Harris, D.A. Shiffler, N.A. Moody, J.J. Petillo, and A.J. Jensen, "Thermal-field and photoemission from meso- and micro-scale features: Effects of screening and roughness on characterization and simulation", J. Appl. Phys. **125**(23), 234303 / 1-25 (2019). 10.1063/1.5097149

Hemispheric feature emittance

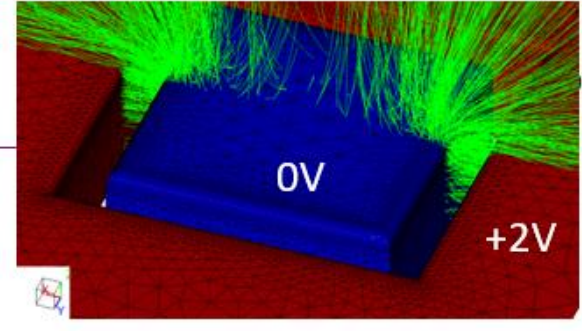
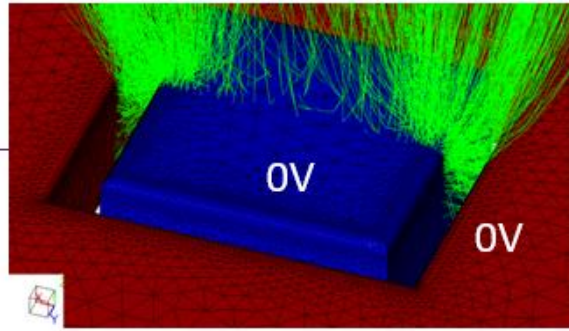
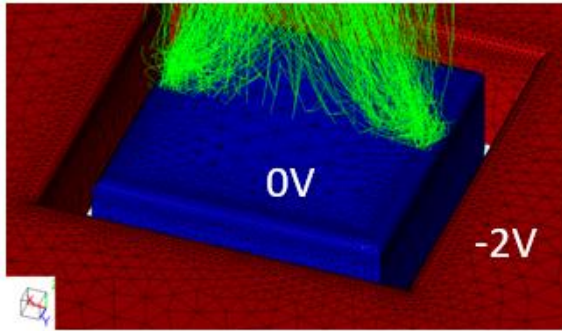


Emittance dominated cases come up quickly

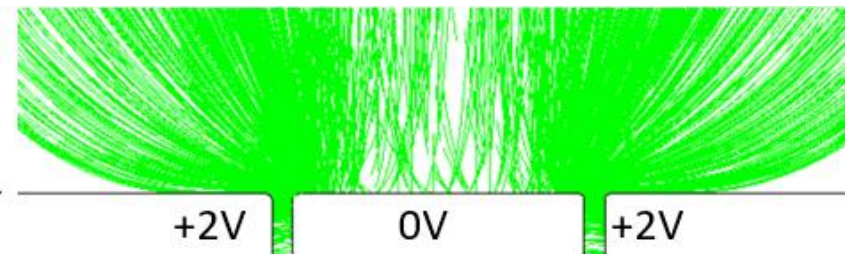
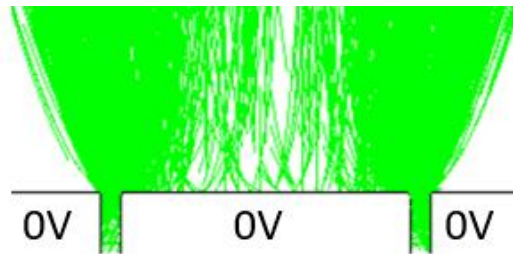
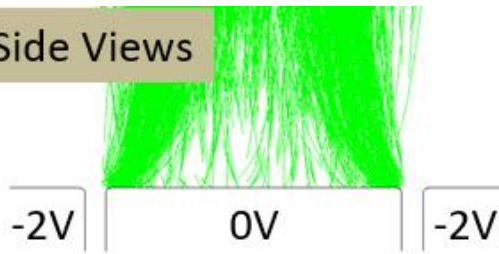


For a flat surface noise dominates and emittance grows slowly

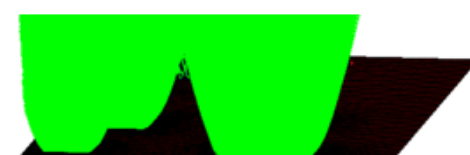
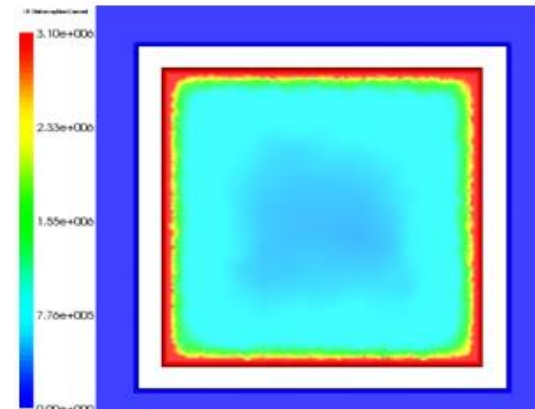
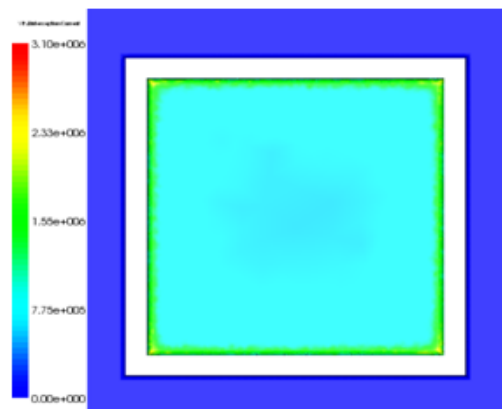
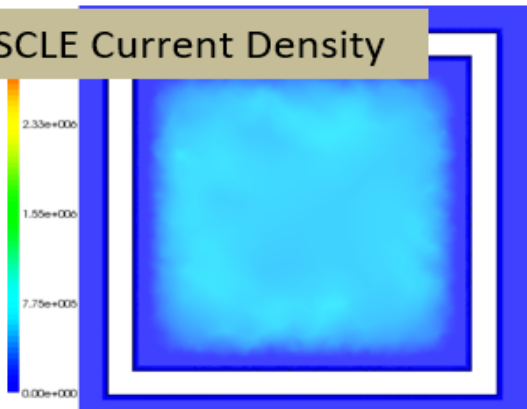
Space Charge and Patch Fields Modify Emission Characteristics for Thermionic



Side Views

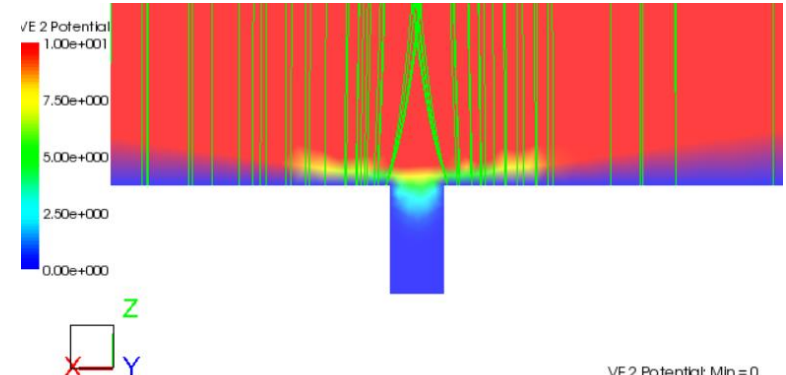
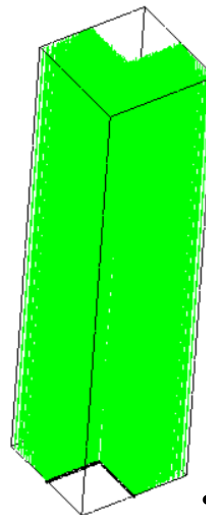
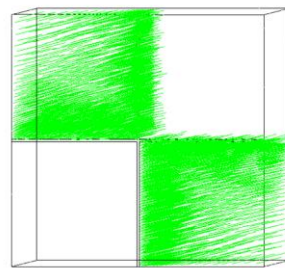
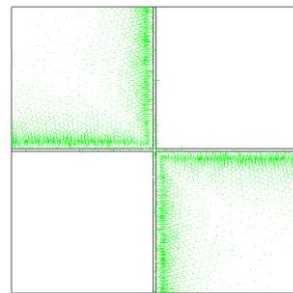
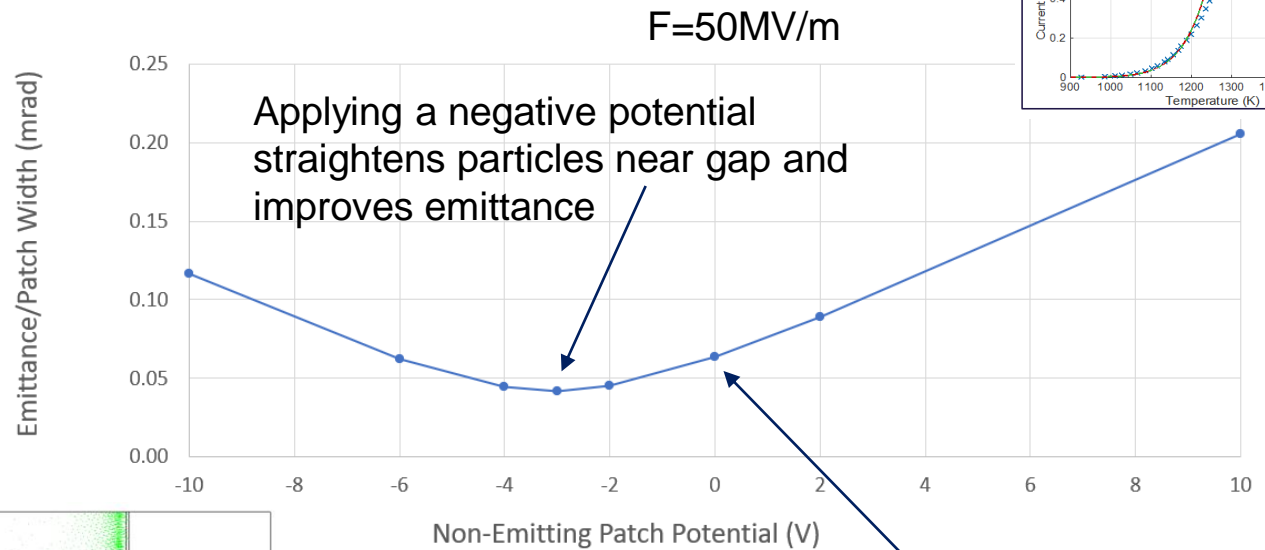
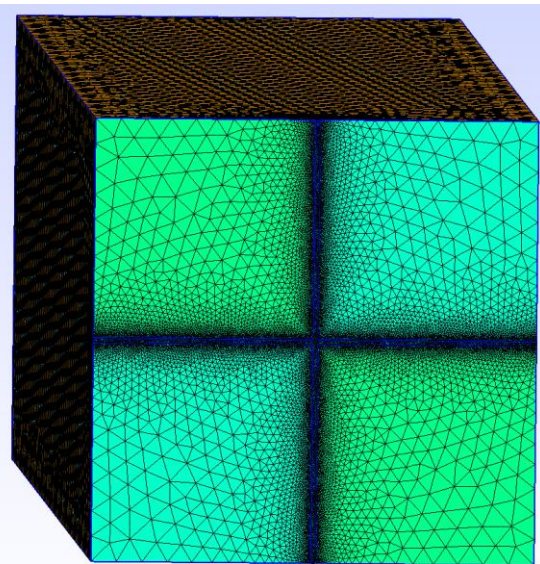
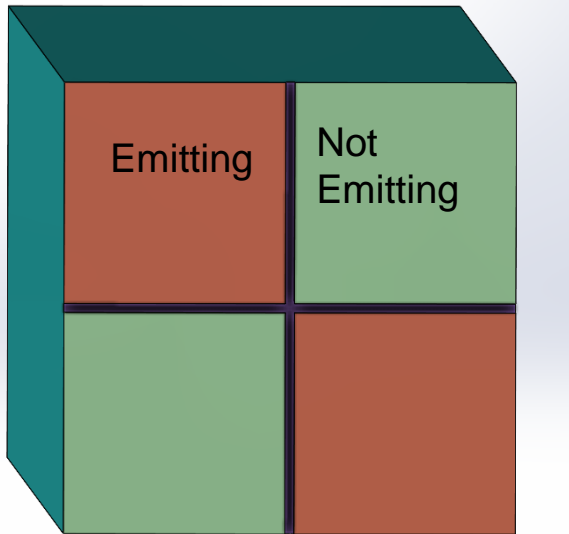
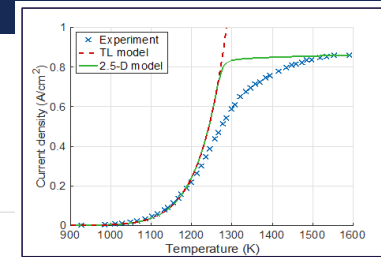


SCLE Current Density



Chemical Roughness: Variation in Work Function / Effective Potential

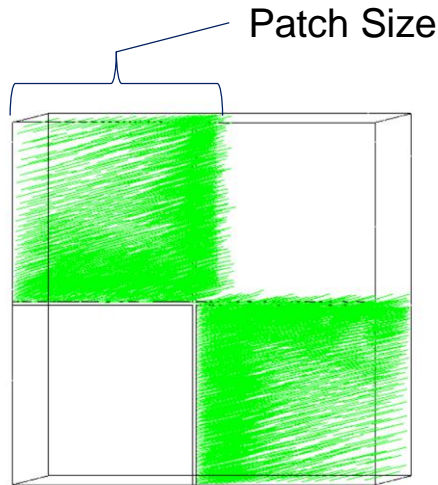
In thermionic emission, intrinsic emittance and detail of emitted distributions are affected by work function variations. Effective variations in surface potentials have a microscopic beam optics effect – leading to MTE



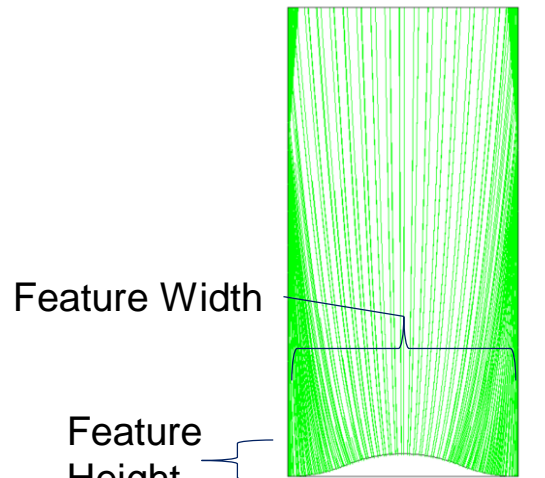
VE 2 Potential: Min = 0
VE 2 Potential: Max = 10

- Gap between patches increases emittance
- Voltage differences increase emittance

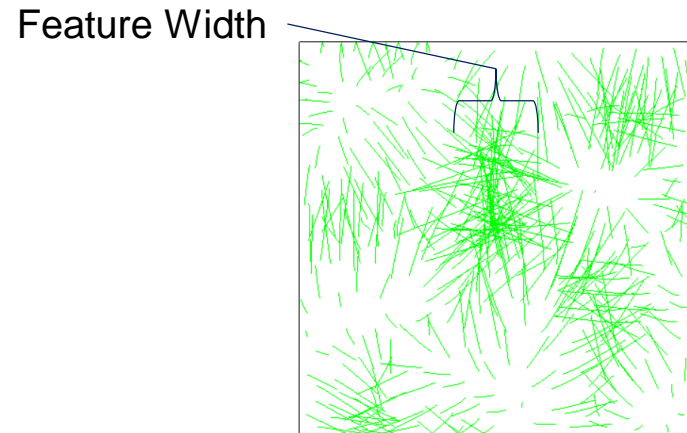
Application: 10 micron Patch 1 micron Feature



Patch Emission



Rough Emission



Rough Emission

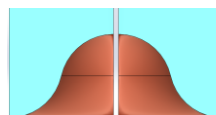
For a 10um Patch

Patch Potential (V)	Emittance (mm*mrad)
-10	1.17E-03
-6	6.23E-04
-4	4.45E-04
-3	4.20E-04
-2	4.51E-04
0	6.34E-04
2	8.90E-04
10	2.06E-03



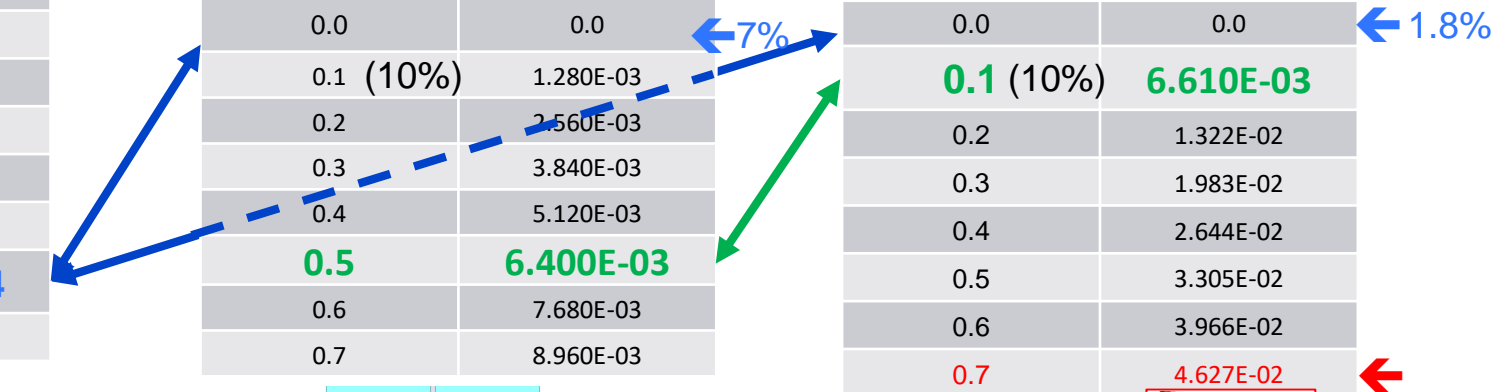
For a 1um Feature

1um Width Feature Height (um)	Emittance (mm*mrad)
0.0	0.0
0.1 (10%)	1.280E-03
0.2	2.560E-03
0.3	3.840E-03
0.4	5.120E-03
0.5	6.400E-03
0.6	7.680E-03
0.7	8.960E-03



For a 1um Feature

1um Width Feature Height (um)	Emittance (mm*mrad)
0.0	0.0
0.1 (10%)	6.610E-03
0.2	1.322E-02
0.3	1.983E-02
0.4	2.644E-02
0.5	3.305E-02
0.6	3.966E-02
0.7	4.627E-02



- I. Multiple sources of emittance leading to MTE when no space charge is present**
- II. Chemical Contribution to Emittance (Work Function Variation)**
 - Significant but perhaps not the largest source of intrinsic emittance
- III. Artificial (Ordered) Geometric Surface Array Contribution to Emittance**
 - Underestimates the emittance due to rough surface features
- IV. Less Artificial (Non-Ordered) Geometric Surface Array Contribution to Emittance**
 - Model expected to better estimate the intrinsic emittance
- V. Comparison of Contributions to Emittance (1 μm feature vs. 10 μm WF patch)**
 - Jensen rough surface model indicates an order of magnitude increase in emittance over a 2 V work function patch emittance
- VI. Next step: Include the effects of space charge**